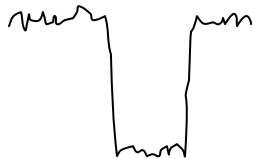


EBL Field Correction Procedure

Field correction should be performed prior to exposure when stitching fields together. It is also performed as part of the overlay process (see EBL Overlay Procedure).

The SEM should be in Exposure mode when performing field correction

1. Click on the field correction button in the exposure menu
2. Verify that the correct field size is selected (field size matches the CAD field size)
3. Click "Start"
 - a. The stage will move to the reference position
 - b. Confirm or optimize focus and astigmatism
4. Click "OK" in the Exposure Menu window and follow the instructions in the Exposure Menu window
 - a. The stage will move to the field correction marks
 - b. Turn off beam blanking
 - c. Move the mark to the center of the cross (make sure the cross position is initialized)
 - d. Change to Slow Scan with Speed = 1
 - e. Click on "CB Monitor" in the Scan Window
 - f. Adjust the brightness and contrast to minimize the noise and maximize the step height in the CB scan. The image will look a little washed out. Note: Re-clicking on "CB monitor" will refresh the intensity scan.



- g. Click on OK, and the system will perform the field correction
5. When field correction is completed, click "OK" and change back to the CAD PC and click "Quit" in the Field Correction Menu